

Microwave multi-beam generation using an anisotropic metasurface

Ioannis Iliopoulos⁽¹⁾, Mauro Ettore*⁽¹⁾, Ronan Sauleau⁽¹⁾, Mounir Teniou⁽²⁾, Massimiliano Casaletti⁽²⁾, Patrick Potier⁽³⁾, and Philippe Pouliguen⁽⁴⁾

(1) Institut d'Electronique et de Télécommunications de Rennes (IETR), UMR CNRS 6164, Université de Rennes 1, 35042 Rennes Cedex, France.

(2) Sorbonne Universités, University Pierre and Marie Curie Paris 06, Unité de Recherche 2 (UR2), Laboratoire d'Electronique et Electromagnétisme (L2E), F-75005 Paris, France

(3) Information Superiority, Direction Générale de l'Armement, 35170 Bruz, France

(4) Strategy Directorate, Direction Générale de l'Armement, 75509 Paris, France

This paper describes the generation of four focused beams originating from a single antenna aperture, practically implemented by an anisotropic metasurface. The apparatus is fed using a single coaxial cable and is capable of generating four focused beams at a distance equal to the radius of the structure. Specifically, the radius of the structure is 5λ and the shaping plane is located at a vertical distance of $z=5\lambda$ (Fig. 1a). The frequency of operation is 20 GHz.

The procedure for the generation of the multiple beams is as follows. The theoretical derivation of the aperture field (E_{AP}) is accomplished using a near-field shaping technique based on a back-propagation optimization scheme (M. Ettore et al., TAP, 62, 4, 1991-1999, 2014). This technique has been extended in order to handle the intensity of the field and not only a single component (scalar). In order to achieve that, a four-beam mask, which enforces a radial polarization (along ρ) to the field on the shaping plane has been elaborated. The imposed polarization means that two of the beams are quasi x -polarized (beams along x axis) and the other two are quasi y -polarized (beams along y axis). Fig. 1b shows the aperture distribution, resulting from the optimization. The four beams at the shaping plane are illustrated in Fig. 1c.

The metasurface, etched on top of a thin substrate, acts as a tensorial surface impedance boundary and is based on circular patches of different diameters. In order to achieve the necessary anisotropy, a varying sector of the patches is removed. The patches are then rotated accordingly. Possible applications include sensing and high-speed near-field communications. A prototype and measurements are expected by the time of the conference.

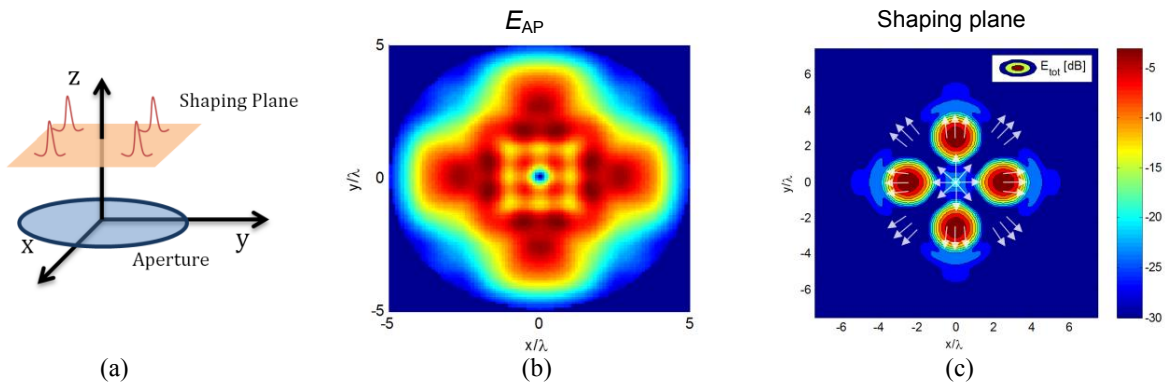


Figure 1. (a) Problem set-up, (b) theoretical aperture distribution of the multiple beam generation and (c) the four beams at the shaping plane (the field direction is shown with white arrows).